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Bib Data Sheet

CONFIRMATION NO. 2084

SERIAL NUMBER 10/779,733	FILING DATE 02/18/2004	CLASS 438	GROUP ART UNIT 2818	ATTORNEY DOCKET NO. 253/006 CIP 2
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APPLICANTS

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** CONTINUING DATA ***

This application is a CIP of 10/278,992 10/24/2002
which is a DIV of 09/686,624 10/12/2000 PAT 6,706,646

** FOREIGN APPLICATIONS ***

REPUBLIC OF KOREA 2003-10159 02/18/2003
REPUBLIC OF KOREA 2000-23448 05/02/2000

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

05/10/2004

Foreign Priority claimed 35 USC 119 (a-d) conditions met	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 8	TOTAL CLAIMS 25	INDEPENDENT CLAIMS 2
Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged Examiner's Signature: <i>M. Lee</i> Initials: <i>ML</i>	KOREA, REPUBLIC OF	DRAWING 8	CLAIMS 25	INDEPENDENT CLAIMS 2

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TITLE

Method of forming a silicon oxide layer in a semiconductor manufacturing process

 All Fees